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PATENT APPLICATION

**RESPONSE UNDER 37 CFR §1.116
EXPEDITED PROCEDURE
TECHNOLOGY CENTER ART UNIT 3723**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Makoto KOBAYASHI et al.

Group Art Unit: 3723

Application No.: 09/830,434

Examiner: H. Shakeri

Filed: April 26, 2001

Docket No.: 109352

For: POLISHING PAD AND POLISHING METHOD FOR SEMI-CONDUCTOR WAFER


TRANSMITTAL OF COURTESY COPY

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Attached is a courtesy copy of an Amendment After Final Rejection that was filed on
September 17, 2003 in the above-captioned patent application.

Respectfully submitted,


William P. Berridge
Registration No. 30,024

Christopher W. Brown
Registration No. 38,025

Joel S. Armstrong
Registration No. 36,430

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SEP 23 2003

TECHNOLOGY CENTER R3700

WPB/CWB/JSA:amw

Date: September 22, 2003

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

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AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116

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P.O. Box 1450
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Sir:

In reply to the June 17, 2003 Office Action, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.